

Semiconductor wafer handler

ABSTRACT OF THE INVENTION

5 A semiconductor wafer handler comprises a ring (70)
attached to a hub (80) by a plurality of spokes (90). Vacuum is
applied to the surface of the semiconductor wafer through
orifices (100) containing in the ring (70). Water and/or
nitrogen can be applied to the surface of the semiconductor
10 wafer through orifices (110) contained in the spokes (90).